

IN THE CLAIMS:

Please AMEND claims 1, 11, 32, and 34 and ADD claims 35 and 36 in accordance with the following:

1. (CURRENTLY AMENDED) A heating crucible for a deposition apparatus, comprising:
a main body having a space which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in an upper wall of the main body; and

an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the surface having the area that faces the nozzle and whose edges are defined by the surface and which are bordered on outsides thereof by an inner wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the opening.

2. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein:
the inner member further comprises a baffle board formed on the area that faces the nozzle, and

the one or more openings are formed around an edge of the baffle board.

3. (ORIGINAL) The heating crucible of claim 2, wherein the inner member further comprises at least one fixing portion which extends upward from the baffle board and supports the baffle board.

4. (ORIGINAL) The heating crucible of claim 2, wherein the inner member further comprises at least one fixing portion which extends downward from the baffle board and supports the baffle board.

5. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein the one or more openings are continuously or discontinuously formed along the edge of the inner member.

6. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein the one or more openings are formed at regular intervals around the edge of the inner member.

7. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein a sum of areas of the one or more openings of the inner member is equal to or greater than an area of the nozzle.

8. (ORIGINAL) The heating crucible of claim 1, wherein a distance between the nozzle and the inner member is from a radius of the nozzle to 9/10 of a distance between the nozzle and an inner bottom surface of the main body.

9. (ORIGINAL) The heating crucible of claim 1, wherein the main body comprises a cap on which the nozzle is formed and a main body part in which the space is formed.

10. (ORIGINAL) The heating crucible of claim 1, further comprising a heater which is provided to the main body and/or the nozzle.

11. (CURRENTLY AMENDED) A deposition apparatus for forming a deposition film on a substrate, comprising:

a vacuum chamber which receives the substrate; and

a heating crucible which is installed opposite to the substrate and vaporizes an organic compound provided thereto, wherein the heating crucible comprises:

a main body having a space which receives the organic compound and a nozzle through which the organic compound, once vaporized, is discharged, the nozzle being defined in an upper wall of the main body, and

an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the surface having the area that faces the nozzle and whose edges are defined by the surface and an inner wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the opening
an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the area that faces the nozzle and which are bordered on outsides thereof by an inner wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the opening.

12. (PREVIOUSLY PRESENTED) The deposition apparatus of claim 11, wherein: the

inner member further comprises a baffle board formed on the area that faces the nozzle, and the one or more openings are formed around the edge of the baffle board.

13. (ORIGINAL) The deposition apparatus of claim 12, wherein the inner member further comprises at least one fixing portion which extends upward from the baffle board and supports the baffle board.

14. (ORIGINAL) The deposition apparatus of claim 12, wherein the inner member further comprises at least one fixing portion which extends downward from the baffle board and supports the baffle board.

15. (PREVIOUSLY PRESENTED) The deposition apparatus of claim 11, wherein the one or more openings are formed at regular intervals around the edge of the inner member.

16. (PREVIOUSLY PRESENTED) The deposition apparatus of claim 11, wherein a sum of areas of the one or more openings of the inner member is equal to or greater than an area of the nozzle.

17. (ORIGINAL) The deposition apparatus of claim 11, wherein a distance between the nozzle and the inner member is from a radius of the nozzle and 9/10 of a distance between the nozzle and an inner bottom surface of the main body.

18. (ORIGINAL) The deposition apparatus of claim 11, wherein the main body comprises a cap on which the nozzle is formed and a main body part in which the space is formed.

19. (ORIGINAL) The deposition apparatus of claim 11, wherein the heating crucible further comprises a heater which is provided to the main body and/or the nozzle.

20. (ORIGINAL) The deposition apparatus of claim 11, wherein the inner member is one of an inner plate having one continuous opening formed around an edge of an area thereof, and an inner plate having a plurality of openings formed at a predetermined intervals around an edge of an area thereof.

21. (ORIGINAL) The heating crucible of claim 1, further comprising a temperature sensing unit which senses a temperature of the organic compound.

22. (ORIGINAL) The heating crucible of claim 1, wherein:
the inner member further comprises a baffle board formed on the area that faces the nozzle, and
the baffle board is narrower than a sectional area of the space.

23. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein the one or more openings have a predetermined area so as to prevent a pressure difference between a space below the inner member and a space above the inner member.

24. (ORIGINAL) The heating crucible of claim 1 wherein the nozzle has a vertical axis that does not match with that of the opening so as to prevent the organic compound, in a predetermined form, from being transmitted through the nozzle.

25. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein: the inner member further comprises a baffle board formed on the area that faces the nozzle, and the baffle board blocks the organic compound, in a form of a lump, from being transmitted through the nozzle.

26. (ORIGINAL) The heating crucible of claim 1, wherein the inner member has a cross-section that is substantially the same as that of the space of the main body.

27-31. (CANCELED)

32. (CURRENTLY AMENDED) A method of producing an electroluminescent (EL) device having an organic compound, the method comprising:

obtaining a substrate of the EL device;
depositing a layer of the organic compound on the substrate using a deposition apparatus having a heating crucible including a main body which receives the organic compound, a nozzle defined in an upper wall of the main body, and an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the surface having the area that faces the nozzle and whose edges are defined by the surface and an inner wall of the main body, so as to transmit the organic compound therethrough when vaporized, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the opening ~~an inner member suspended from an upper edge of the main body to face the nozzle having at least one opening therein and~~

~~bordered on an outside thereof by an inner wall of the main body to transmit the organic compound having a predetermined form therethrough, the upper wall being perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the opening; and~~

deflecting the transmitted organic compound via the upper wall of the main body.

33. (ORIGINAL) The method of claim 32, wherein the inner member prevents the organic compound, in a form of a lump, from being deposited on the substrate.

34. (CURRENTLY AMENDED) A heating crucible for a deposition apparatus, comprising:
a main body having a space which receives an organic compound and a nozzle through which the organic compound, once vaporized, is discharged, the nozzle being defined in an upper wall of the main body; and an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the surface having the area that faces the nozzle and whose edges are defined by the surface and an inner wall of the main body, so as to transmit the vaporized organic compound therethrough, an inner member, including a surface having an area facing the nozzle, the inner member being suspended from an upper edge of the main body and having one or more openings, which are formed in the area that faces the nozzle and which are bordered on outsides thereof by an inner wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall of the main body faces the one or more openings and is substantially perpendicular to a path traveled by the transmitted vaporized organic compound.

35. (NEW) A heating crucible for a deposition apparatus, comprising:

a main body having a space therein defined by a cylindrical wall and an upper wall which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in the upper wall of the main body; and

a baffle board parallel with the upper wall, having one or more openings formed therein, that is suspended from an upper edge of the wall of the main body, the openings being bordered on outsides thereof by the wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the one or more openings.

36. (NEW) A deposition apparatus for forming a deposition film on a substrate,

comprising:

a vacuum chamber which receives the substrate; and

a heating crucible which is installed opposite to the substrate and vaporizes an organic compound provided thereto, wherein the heating crucible comprises:

a main body having a space therein defined by a cylindrical wall and an upper wall which receives the organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in the upper wall of the main body; and

a baffle board parallel with the upper wall, having one or more openings formed therein, that is suspended from an upper edge of the wall of the main body, the openings being bordered on outsides thereof by the wall of the main body, so as to transmit the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the one or more openings.